LISTING OF THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. **(Currently Amended)** An apparatus for performing a predetermined process on a group of substrates, the processing procedure of said group of substrates being determined for each substrate unit to be processed including at least one substrate, said apparatus comprising:

a plurality of cells each including:[[;]]

at least one processing unit;

at least one substrate inlet;

a plurality of substrate outlets;

a transport element for transporting a substrate between said at least one processing unit, said at least one substrate inlet and said plurality of substrate outlets; and

a controller for controlling said at least one processing unit and said transport element,

wherein said controller in each of said plurality of cells controls said transport element so that a first substrate received into each cell by way of said at least one substrate inlet is transferred outwardly of each cell by way of one of said plurality of substrate outlets which is determined by a first transport setting established for each cell and for a first substrate unit to which said first substrate belongs, so that a second substrate received into each cell by way of said at least one substrate inlet is transferred outwardly of each cell by way of another one of said plurality of substrate outlets which is determined by a second transport setting established for each cell and for a second substrate unit to which said second substrate belongs, and so that said first and second substrates determined to be transferred outwardly by way of said one and said another one of said plurality of substrate outlets by said first and second transport ~~setting~~ settings are transferred outwardly in the order in which said first and second substrates are [[made]] ready for outward transfer.

2. **(Currently Amended)** The apparatus according to claim 1, further comprising

a plurality of substrate rest parts provided between adjacent two of said plurality of cells,

one of said plurality of substrate rest parts serving as said at least one substrate inlet of one of said two adjacent cells, and as one or another one of said plurality of substrate outlets of the other of said two adjacent cells,

the remainder of said plurality of substrate rest parts serving as one or another one of said plurality of substrate outlets of said one of said two adjacent cells, and as said at least one substrate inlet of said other of said two adjacent cells,

wherein said controller in each of said plurality of cells determines the order in which substrates are to be transferred outwardly by way of said one of said substrate outlets of each cell by referencing a substrate placement state signal and said transport setting, said substrate placement state signal being applied from a predetermined sensor and indicating whether or not a substrate is placed on a corresponding one of said substrate rest parts.

3. (Original) The apparatus according to claim 2, wherein

said predetermined sensor is provided in said corresponding one of said substrate rest parts.

4. (Original) The apparatus according to claim 2, wherein

said predetermined sensor is provided in said transport element.

5. (Currently Amended) ~~An apparatus for performing a predetermined process on a group of substrates, the processing procedure of said group of substrates being determined for each substrate unit to be processed including at least one substrate, said apparatus comprising~~

~~a plurality of cells each including:~~

~~at least one processing unit;~~

~~a transport element for transporting a substrate; and~~

~~a controller for controlling said at least one processing unit and said transport element;~~

The apparatus according to claim 1, wherein said controller in each of said plurality of cells controls said at least one processing unit and said transport element so that [[a]] said first

substrate belonging to [[a]] said first substrate unit is received into each cell before the completion of an intra-cell process of [[a]] said second substrate ~~preceding said first substrate and~~ belonging to [[a]] said second substrate unit ~~different in transport setting from said first substrate unit~~, and so that said first and second substrates are processed and transported in accordance with the transport setting for the first and second substrate units, respectively.

6. (Canceled)

7. (Original) The apparatus accordingly to claim 1, wherein

said at least one processing unit in at least one of said plurality of cells includes at least one of a processing unit for processing a substrate using a chemical solution and a thermal processing unit for heating or cooling a substrate.

8. (Currently Amended) A method of transporting substrates in a substrate processing apparatus, said substrate processing apparatus processing and transporting substrates belonging to a plurality of substrate units to be processed, each of said substrate units including at least one substrate, said substrate processing apparatus including a plurality of cells, each of said plurality of cells including at least one processing unit, at least one substrate inlet, a plurality of substrate outlets, and a transport element for transporting a substrate between said at least one processing unit, said at least one substrate inlet and said plurality of substrate outlets, said method comprising the steps of:

(a) receiving a substrate into each cell by way of said at least one substrate inlet; and

(b) transferring said substrate outwardly of each cell by way of any of said plurality of substrate outlets,

wherein, in said step (b), [[said]] a first substrate is transferred outwardly by way of one of said plurality of substrate outlets determined by a first transport setting established for each cell and for ~~one of said substrate units to which said substrate said substrate belongs, and~~ a first substrate unit to which said first substrate belongs,

wherein in said step (b), a second substrate is transferred outwardly by way of another one of said plurality of substrate outlets determined by a second transport setting established for each cell and for a second substrate unit to which said second substrate belongs, and

wherein, in said step (b), said first and second substrates determined to be transferred outwardly by way of said one and another one of said plurality of substrate outlets by said first and second transport ~~setting~~ settings are transferred outwardly in the order in which said first and second substrates are made ready for outward transfer.

9. (Currently Amended) The method according to claim 8, wherein:

said substrate processing apparatus further includes a plurality of substrate rest parts between adjacent two of said plurality of cells,

one of said plurality of substrate rest parts serving as said at least one substrate inlet of one of said two adjacent cells, and as one or another one of said plurality of substrate outlets of the other of said two adjacent cells,

the remainder of said plurality of substrate rest parts serving as one or another one of said plurality of substrate outlets of said one of said two adjacent cells, and as said at least one substrate inlet of said other of said two adjacent cells: and

the order in which substrates are to be transferred outwardly by way of said one of said substrate outlets of each cell is determined by referencing a substrate placement state signal and said transport setting, said substrate placement state signal indicating whether or not a substrate is placed on a corresponding one of said substrate rest parts.

10. (Currently Amended) ~~A method of processing substrates in a substrate processing apparatus, said substrate processing apparatus processing and transporting substrates belonging to a plurality of substrate units to be processed, each of said substrate units including at least one substrate, said substrate processing apparatus including a plurality of cells, each of said plurality of cells including at least one processing unit, and a transport element for transporting a substrate, said method comprising the steps of:~~

~~(a) receiving a substrate into each cell, and~~

~~(b) transporting said substrate in each cell by means of said transport element,~~

~~wherein, in said step (b), a substrate is transported in accordance with transport setting established for each cell and for each substrate unit, and~~

The method according to claim 8, wherein, in said step (a), [[a]] said first substrate belonging to [[a]] said first substrate unit is received into each cell before the completion of an intra-cell process of [[a]] said second substrate ~~preceding said first substrate and~~ belonging to [[a]] said second substrate unit ~~different in transport setting from said first substrate unit~~.

11. (Canceled)

12. (Currently Amended) The apparatus according to claim 1, wherein:

said at least one substrate inlet includes a plurality of substrate inlets;

said at least one processing unit includes a plurality of processing units; and

said controller in each of said plurality of cells allows said transport element to outwardly transfer ~~a substrate~~ said first and second substrates made ready for outward transfer earlier when said first and second substrates belonging to a plurality of substrate units different in transport setting are received into each cell by way of a common one of said plurality of substrate inlets and are subjected to an intra-cell process in a common one of said plurality of processing units.

13. (Canceled)

14. (Currently Amended) The method according to claim 8, wherein:

said at least one substrate inlet includes a plurality of substrate inlets;

said at least one processing unit includes a plurality of processing units; and

~~a substrate~~ said first and second substrates made ready for outward transfer earlier [[is]] are allowed to be transferred outwardly of each cell when said first and second substrates belonging to ~~a plurality of substrate units~~ said first and second substrate units different in transport setting are received into each cell by way of a common one of said plurality of substrate

inlets and are subjected to an intra-cell process in a common one of said plurality of processing units.

15. (Canceled)

16. (New) An apparatus for performing a predetermined process on a group of substrates, the processing procedure of said group of substrates being determined for each substrate unit to be processed including at least one substrate, said apparatus comprising

a plurality of cells each including;

at least one processing unit;

at least one substrate inlet;

a plurality of substrate outlets;

a transport element for transporting a substrate between said at least one processing unit, said at least one substrate inlet and said plurality of substrate outlets; and

a controller for controlling said at least one processing unit and said transport element,

wherein said controller in each of said plurality of cells controls said transport element so that a substrate received into each cell by way of said at least one substrate inlet is transferred outwardly of each cell by way of one of said plurality of substrate outlets which is determined by transport setting established for each cell and for a substrate unit to which said substrate belongs, and so that substrates determined to be transferred outwardly by way of said one of said plurality of substrate outlets by said transport setting are transferred outwardly in the order in which said substrates are made ready for outward transfer;~~, further comprising~~

a plurality of substrate rest parts provided between adjacent two of said plurality of cells,

one of said plurality of substrate rest parts serving as said at least one substrate inlet of one of said two adjacent cells and as one of said plurality of substrate outlets of the other of said two adjacent cells,

the remainder of said plurality of substrate rest parts serving as one of said plurality of substrate outlets of said one of said two adjacent cells and as said at least one substrate inlet of said other of said two adjacent cells,

wherein said controller in each of said plurality of cells determines the order in which substrates are to be transferred outwardly by way of said one of said substrate outlets of each cell by referencing a substrate placement state signal and said transport setting, said substrate placement state signal being applied from a predetermined sensor and indicating whether or not a substrate is placed on a corresponding one of said substrate rest parts.

17. (New) A method of transporting substrates in a substrate processing apparatus, said substrate processing apparatus processing and transporting substrates belonging to a plurality of substrate units to be processed, each of said substrate units including at least one substrate, said substrate processing apparatus including a plurality of cells, each of said plurality of cells including at least one processing unit, at least one substrate inlet, a plurality of substrate outlets, and a transport element for transporting a substrate between said at least one processing unit, said at least one substrate inlet and said plurality of substrate outlets, said method comprising the steps of:

(a) receiving a substrate into each cell by way of said at least one substrate inlet; and

(b) transferring said substrate outwardly of each cell by way of any of said plurality of substrate outlets,

wherein, in said step (b), said substrate is transferred outwardly by way of one of said plurality of substrate outlets determined by transport setting established for each cell and for one of said substrate units to which said substrate said substrate belongs, and

wherein, in said step (b), substrates determined to be transferred outwardly by way of said one of said plurality of substrate outlets by said transport setting are transferred outwardly in the order in which said substrates are made ready for outward transfer, wherein:

said substrate processing apparatus further includes a plurality of substrate rest parts between adjacent two of said plurality of cells,

one of said plurality of substrate rest parts serving as said at least one substrate inlet of one of said two adjacent cells and as one of said plurality of substrate outlets of the other of said two adjacent cells,

the remainder of said plurality of substrate rest parts serving as one of said plurality of substrate outlets of said one of said two adjacent cells and as said at least one substrate inlet of said other of said two adjacent cells: and

the order in which substrates are to be transferred outwardly by way of said one of said substrate outlets of each cell is determined by referencing a substrate placement state signal and said transport setting, said substrate placement state signal indicating whether or not a substrate is placed on a corresponding one of said substrate rest parts.